

ABSTRACT

There is provided a method for manufacturing a passivation film that can reproducibly produce a
5 passivation film with a low concentration of oxygen atoms. A passivation film is manufactured by a method of manufacturing a passivation film, the method including a passivation process in which a substrate on the surface of which at least one of germanium and molybdenum is
10 contained is treated with a passivation gas containing an oxygen-containing compound, which is a compound containing an oxygen atom in the molecule, and hydrogen sulfide to form a passivation film containing a sulfur atom on the surface of the substrate. The concentration
15 of the oxygen-containing compound in the passivation gas is from 0.001 mole ppm to less than 75 mole ppm.

Fig.1